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10/617,578	07/11/2003	Steven P. Nally	108298533US1	3549
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PERKINS COIE LLP			ALANKO, ANITA KAREN	
PATENT-SEA				
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SEATTLE, WA 98111-1247			PAPER NUMBER	
			1765	

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Please find below and/or attached an Office communication concerning this application or proceeding.



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10/617,578

7/11/03

Nally

108298533 US1

EXAMINER

ART UNIT	PAPER
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022406

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Commissioner for Patents

Attached please find an English translation for KR 97-008549. Applicant is requested to consider this in the response to the outstanding office action mailed 2/13/06.

Anita K. Alanko

Anita K Alanko
Primary Examiner
Art Unit: 1765

**MARKING REMOVAL DEVICE FOR SEMICONDUCTOR CHIP PACKAGE AND
MARKING REMOVAL METHOD USING THE DEVICE**

Dong Wan Kye, et al.

KOREAN INTELLECTUAL PROPERTY OFFICE (KR)
PATENT JOURNAL (A)
KOREAN PATENT APPLICATION TEUK 1997-0008549

Int. Cl. ⁶ :	H 01 L 23/544
Filing No.:	Teuk 1995-0022124
Filing Date:	July 25, 1995
Publication Date:	February 24, 1997
Examination request:	Filed

MARKING REMOVAL DEVICE FOR SEMICONDUCTOR CHIP PACKAGE AND
MARKING REMOVAL METHOD USING THE DEVICE

[Ban-do-che chip pa-ki-ji-ui ma-king je-ku-jang-chi mit keu-reul yee-yong-han ma-king
je-ku-bang-bub]

Inventors:	Dong Wan Kye et al.
Applicant:	Samsung Electronics Company

Representative figure

Figure 1

Brief description of the figure

Figure 1 is a diagram showing the marking removal method for semiconductor chip packages of the present invention. Figure 2 is a plan view of a window plate having various pad windows that are used in the marking removing method for semiconductor chip packages of the present invention.

The contents are presented to publish the principal parts and therefore the entire content is not recorded.

Claims

1. Marking removal device for semiconductor chip packages, wherein the device that removes the markings of semiconductor chip packages is equipped with a support section that is extended so that it does not physically contact external leads built into the semiconductor chip package; a window pad formed to expose the marking area of the semiconductor chip package supported by the support section; a window plate that has at least one or more of the aforementioned window pads formed.

2. Marking removal device for semiconductor chip packages of Claim 1, characterized by being surrounded by rubber to prevent static electricity in a certain area of the aforementioned support section.

3. Marking removal device for semiconductor chip packages of Claim 1, wherein the aforementioned support section extends higher than the height of the aforementioned external lead.

4. Marking removal device for semiconductor chip packages of Claim 1, wherein the aforementioned window pad is formed no larger than the semiconductor chip package, when comparing to the size of the aforementioned semiconductor chip package.

5. Marking removal method using a marking removal device for semiconductor chip packages, which includes a step wherein the opposite side of the package markings is pushed into a certain area of the support section of the marking removal device; and a step wherein the markings on the marked face of the package in contact with the device is removed by a chemical removal agent.

6. Marking removal method using the marking removal device for semiconductor chip packages of Claim 5, wherein the aforementioned chemical removal agent is in liquid phase or vapor phase.

7. Marking removal method using the marking removal device for semiconductor chip packages of Claim 5, characterized in that the aforementioned marking removal method using the aforementioned chemical removal agent is a reflow, dipping and spray method.

8. Marking removal method using the marking removal device for semiconductor chip package of Claim 5, characterized by an additional rinse step so as to eliminate the residues of the markings removed by the aforementioned chemical removal agent.

9. Marking removal method using the marking removal device for semiconductor chip package of Claim 8, characterized in that the rinsing agent used in the aforementioned rinse step is distilled water.

} etch

} rinse

Note: Published from contents of the first application.

Figure

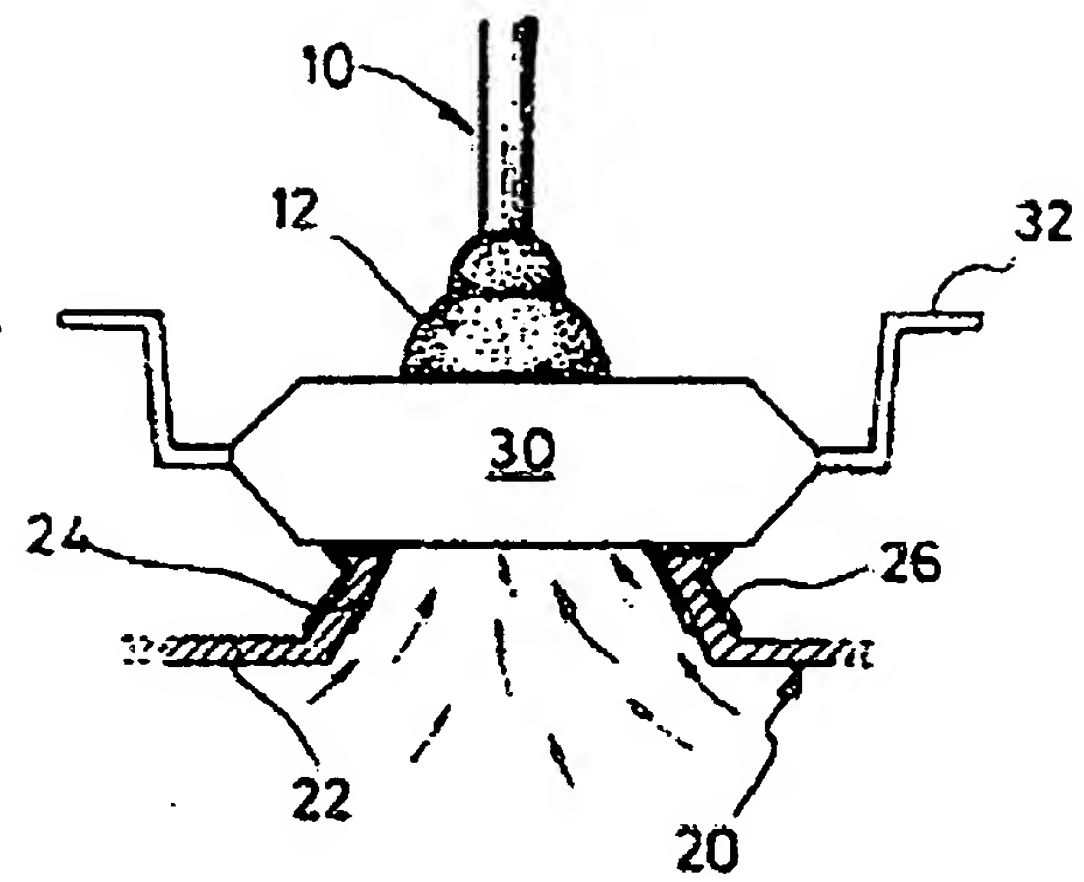


Figure 1

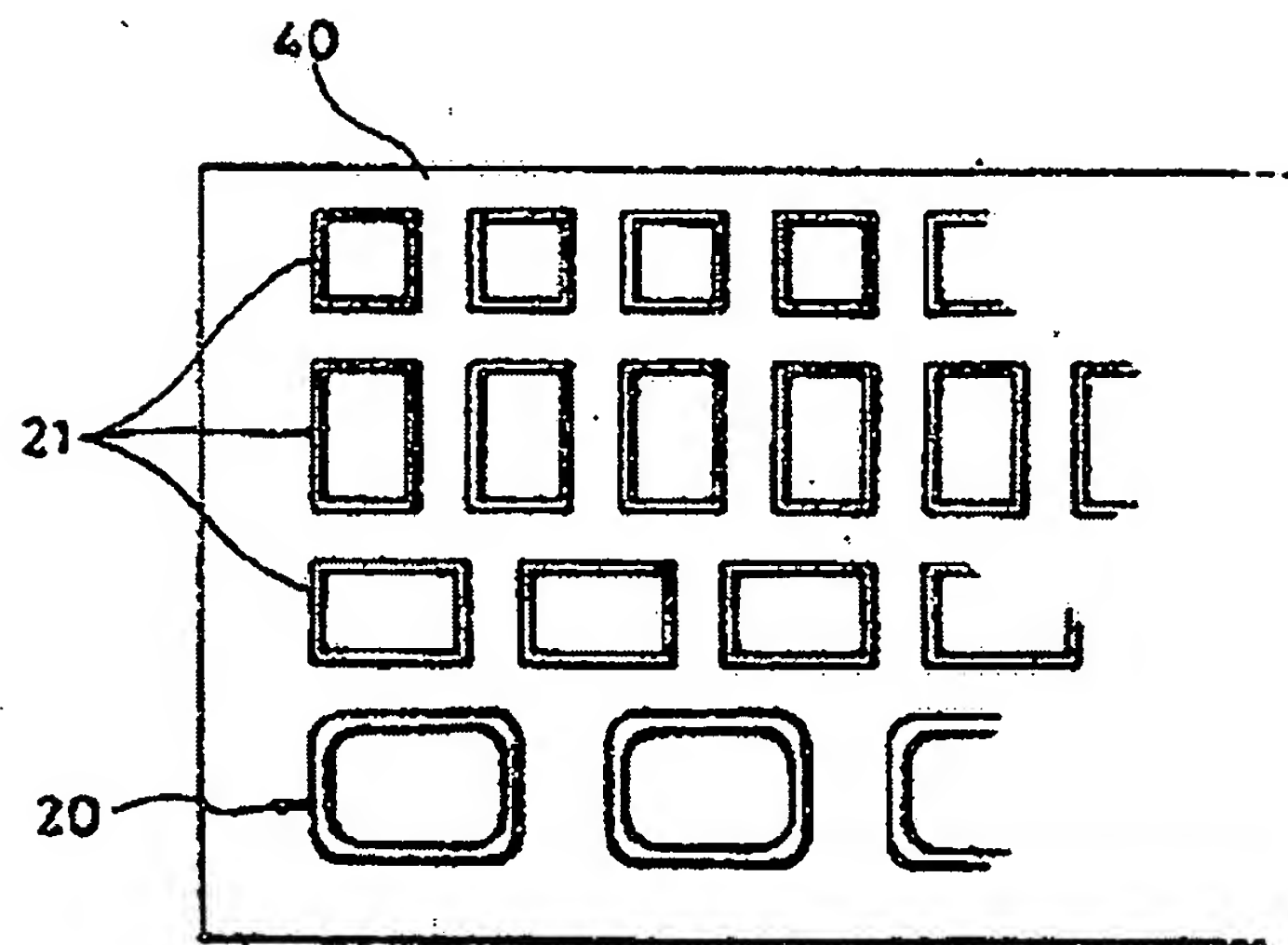


Figure 2